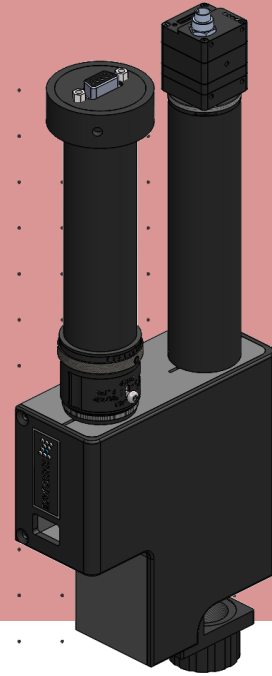# Xper-WLI
(White Light Interferometric Profiler)
by NANO**BASE**

Thickness and profile detection in nanoscale

WLI & PSI mode change function

Industrial application : sample defect / structure / quality verification

Sample types : Nanomaterials, Biomaterials, Chemical structures

Specifications

Measurement Principle
White light phase shift interferometry

Measuring Performance
Three-dimensional surface profile measurements, surface roughness measurements

Z-axis Resolution
1.75 nm (surface measurements noise level)

CCD Resolution
2464 x 2056 pixels

High Stiffness Scanner Range (Piezo)
30μm

Objective Lens Options
10x, 20x, 50x, 100x

Illuminator
LED lamp

Filter Module for PSI
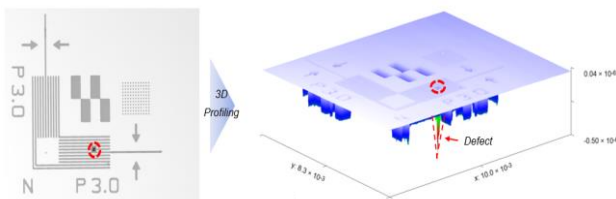532nm, 633nm (Visible range : 400~ 750nm)

PC
- CPU : Octa Core 3.0 GHz
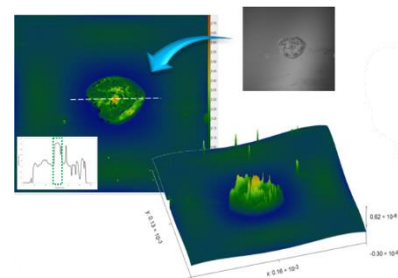- RAM : 16 GB
- Storage : SSD 128 GB
- OS : Windows 10

Software
- Auto experiment condition set
- Post processing : Smoothening / z-axis control factor / offset control
- X/Y axis profile extraction

Analysis Data

Semiconductor device defect analysis

Oral cell analysis